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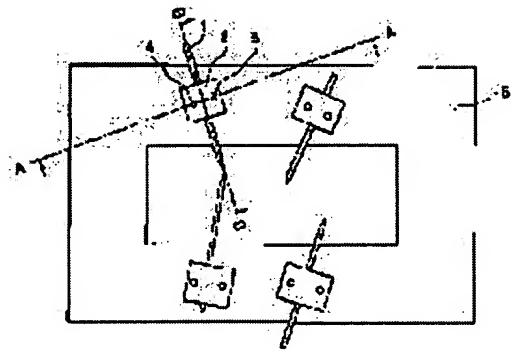
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(54) PROBING DEVICE WITH POSITION ADJUSTING MECHANISM

(57)Abstract:

PURPOSE: To align the probe which detects the characteristic physical value of an electronic circuit to be measured while the probe is brought into contact with an electronic circuit to be measured of a probing device in which the probe is incorporated and fixed with the pad of the object to be measured through simple rotation and forward-backward movement.

CONSTITUTION: This probing device is provided with a probe 1, probe retaining member 2 the one end of which is rotatably held on the upper surface of an insulating board 5, and fixing jigs 3 and 4 which respectively fix the probe 1 and member 2. Since the probe can be easily moved, no long time is required at the time of preparing or replacing a probe card even when the pad position differs among objects to be measured.



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(citation 1)

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Publication Date: October 8, 1993
Application No. H4-57,764 filed March 16, 1992
Inventor: Nobuyuki MAKIOKA
Applicant: K.K. Hitachi Seisakusho

Title of the invention: Probing Apparatus with Position Adjusting Mechanism



(Claim 1)

A probing apparatus wherein probes (1) for contacting and detecting physical properties of a subject electronic circuit are arranged and fixed, characterized in that the probing apparatus is provided with a position adjusting mechanism and comprising an insulating substrate (5), probe holding members (2) each rotatably supported at one end on a top surface of the insulating substrate, and a fixing jig (3, 4) mounted on each of the holding members.

(Abridgment of the description)

Fig. 1 shows a top view of one embodiment of the claimed probing apparatus. Fig. 2 is an enlarged A-A cross sectional view and Fig. 3 is an enlarged B-B cross sectional view. As shown in the figures, the probing apparatus comprises an insulating substrate 5 and a plurality of probing devices arranged thereon. Each probing device comprises a probe 1, a probe holding member 2 having a groove for receiving the probe 1, a fixing jig 3 for fixating the probe holding member 2 to prevent rotation, and a fixing jig 4 for attaching the probe holding member 2 to the substrate 5. When the jigs 3 and 4 are loosened, the probe holding member 2 can be rotated about the jig 4 and the probe 1 can be moved longitudinally. In use, the position of the probe 1 is adjusted with respect to a pad on a circuit to be tested, and the jigs 3 and 4 are then tightened.

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